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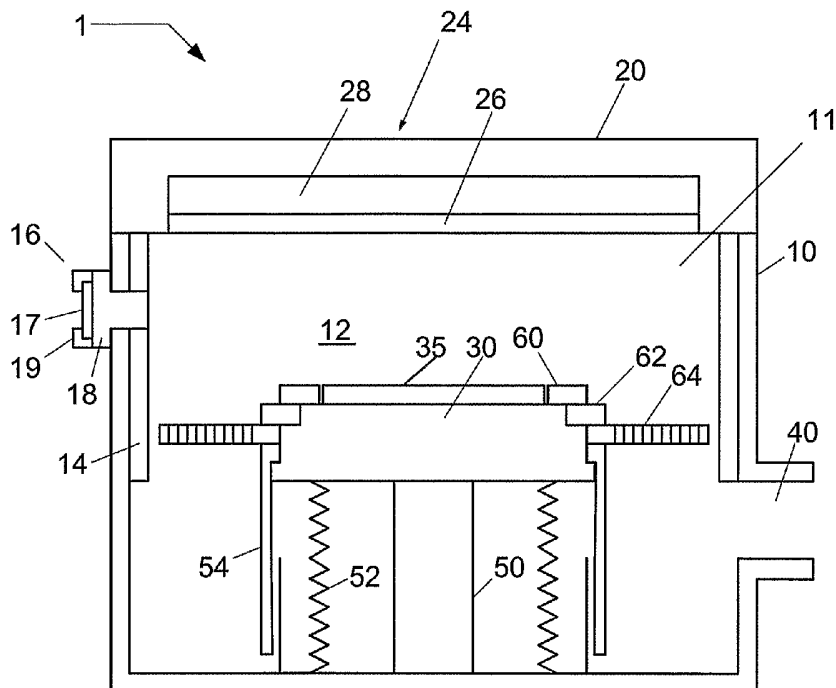
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(54) Title: METHOD AND APPARATUS FOR IMPROVED BAFFLE PLATE



(57) Abstract: An apparatus related to plasma chambers used for processing semiconductor substrates and specifically to improvements in pumping baffle plates used in plasma sources. An apparatus and method for making a baffle plate assembly formed from a modified baffle plate blank wherein a variety of pumping features are formed in the baffle plate blank and opened in a planar material removal operation.

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TITLE OF THE INVENTION

METHOD AND APPARATUS FOR IMPROVED BAFFLE PLATE

FIELD OF THE INVENTION

[0001] The present invention relates to a method and apparatus for utilizing a baffle plate in a plasma processing system, and methods of making the same.

BACKGROUND OF THE INVENTION

[0002] The fabrication of integrated circuits (IC) in the semiconductor industry typically employs plasma to create and assist surface chemistry within a vacuum processing system necessary to remove material from and deposit material to a substrate. In general, plasma is formed within the processing system under vacuum conditions by heating electrons to energies sufficient to sustain ionizing collisions with a supplied process gas. Moreover, the heated electrons can have energy sufficient to sustain dissociative collisions and, therefore, a specific set of gases under predetermined conditions (e.g., chamber pressure, gas flow rate, etc.) are chosen to produce a population of charged species and chemically reactive species suitable to the particular process being performed within the system (e.g., etching processes where materials are removed from the substrate or deposition processes where materials are added to the substrate).

[0003] In the prior art, plasma has been attenuated in the process chamber utilizing various baffle plates. One function of the attenuation has been to improve the confinement of the plasma in the process chamber. Another function of these

plates has been to keep plasma from entering areas where harm could occur to mechanical components. Prior baffle plate designs utilize slots or orifices of various configurations to attenuate or confine the plasma. Typical baffle plates utilize hundreds of slot features or thousands of orifice features. These slot and orifice features add considerable cost to produce the typical baffle plate.

SUMMARY OF THE INVENTION

[0004] The present invention relates to a method of fabricating a baffle plate assembly, surrounding a substrate holder in a plasma processing system comprised of forming a baffle plate blank and subsequently forming one or more pumping passageways wherein one or more features of the baffle plate blank are modified by planar material removal forming the pumping passages.

[0005] The present invention also relates to a baffle plate assembly, which surrounds a substrate holder in a plasma processing system and comprises a baffle plate blank having one or more pumping passages wherein one or more features of the baffle plate blank are modified by planar material removal forming the pumping passages.

[0006] The present invention also relates to a plasma process apparatus with baffle a plate assembly comprising a process chamber, a plasma generating system configured and arranged to produce a plasma in the process chamber, a gas source configured to introduce gases into the process chamber, a pressure control system to maintain a selected pressure within the process chamber, a substrate holder configured to hold a substrate during substrate processing,

and a baffle plate assembly. The baffle plate assembly is disposed radially outward from the substrate and formed from a baffle plate blank with one or more pumping passages formed from planar material removal from the baffle plate blank.

BREIF DESCRIPTION OF THE DRAWINGS

[0007] The accompanying drawings, which are incorporated in and constitute a part of the specification, illustrate embodiments of the invention, and together with the general description given above and the detailed description of the embodiments given below, serve to explain the principles of the invention wherein:

[0008] FIG. 1 illustrates a schematic block diagram of a plasma processing system according to an embodiment of the present invention;

[0009] FIG. 2 presents a method of fabricating a baffle plate assembly, surrounding a substrate holder in a plasma processing system;

[0010] FIG. 3A presents a plan view of a baffle plate blank according to the present invention;

[0011] FIG. 3B presents a cross-sectional view of the baffle plate blank of FIG. 3A;

[0012] FIG. 3C presents a cross-sectional view of the baffle plate blank of FIG. 3B, after planar material removal;

[0013] FIG. 4A presents a plan view of a baffle plate according to another embodiment of the present invention;

[0014] FIG. 4B presents a plan view of a baffle plate according to another embodiment of the present invention; and

[0015] FIG. 4C presents a plan view of a baffle plate according to another embodiment of the present invention.

DESCRIPTION OF THE PREFERRED EMBODIMENTS

[0016] In plasma processing, a baffle plate can be employed to aid in confining the plasma to the processing region adjacent to the substrate, as well as to effect the uniformity of fluid mechanic properties in the processing region adjacent to the substrate. For conventional plasma processing systems, the baffle plate is configured to surround the substrate holder and, in many cases, the baffle plate is physically coupled to the substrate holder using fasteners. In general, the baffle plate comprises a plurality of openings to permit the passage of process gasses, reactants and reaction products to the vacuum pumping system.

[0017] According to an embodiment of the present invention, a plasma processing system 1 is depicted in FIG. 1 comprising a plasma processing chamber 10, an upper assembly 20, an electrode plate assembly 24, a substrate holder 30 for supporting the substrate 35, and a pumping duct 40 coupled to a vacuum pump (not shown) for providing a reduced pressure atmosphere 11 in plasma processing chamber 10. Plasma processing chamber 10 can facilitate the formation of a process plasma in process space 12 adjacent to the substrate 35. The plasma processing system 1 can be configured to process substrates of any size, such as 200mm substrates, 300mm substrates, or larger.

[0018] In the illustrated embodiment, electrode plate assembly 24 comprises an electrode plate 26 and an electrode 28. In an alternate embodiment, upper assembly 20 can also comprise a cover, a gas injection assembly, and/or an

upper impedance match network. The electrode plate assembly 24 can be coupled to an RF source. In another alternate embodiment, the upper assembly 20 comprises a cover coupled to the electrode plate assembly 24, wherein the electrode plate assembly 24 is maintained at an electrical potential equivalent to that of the plasma processing chamber 10. For example, the plasma processing chamber 10, the upper assembly 20, and the electrode plate assembly 24 can be electrically connected to ground potential.

[0019] Plasma processing chamber 10 can further comprise an optical viewport 16 coupled to a deposition shield. Optical viewport 16 can comprise an optical window 17 coupled to the backside of an optical window deposition shield 18, and an optical window flange 19 can be configured to couple the optical window 17 to the optical window deposition shield 18. Sealing members, such as O-rings, can be provided between the optical window flange 19 and the optical window 17, between the optical window 17 and the optical window deposition shield 18 and the plasma processing chamber 10. Optical viewport 16 can permit monitoring of optical emission from the processing plasma in process space 12.

[0020] Substrate holder 30 can further comprise a vertical translational device 50 surrounded by a bellows 52 coupled to the substrate holder 30 and the plasma processing chamber 10, and configured to seal the vertical translational device 50 from the reduced pressure atmosphere 11 in plasma processing chamber 10. Additionally, a bellows shield 54 can be coupled to the substrate holder 30 and configured to protect the bellows 52 from the processing plasma. Substrate holder 10 can further be coupled to a focus ring 60, and/or

a shield ring 62. Furthermore, a baffle plate 64 can extend about a periphery of the substrate holder 30.

[0021] Substrate 35 can be transferred into and out of plasma processing chamber 10 through a slot valve (not shown) and/or a chamber feed-thru (not shown) via a robotic substrate transfer system where it is received by substrate lift pins (not shown) housed within substrate holder 30 and mechanically translated by devices housed therein. Once substrate 35 is received from substrate transfer system, it is lowered to an upper surface of substrate holder 30.

[0022] Substrate 35 can be affixed to the substrate holder 30 via an electrostatic clamping system, or a mechanical clamping system. Furthermore, substrate holder 30 can further include a cooling system including a re-circulating coolant flow that receives heat from the substrate holder 30 and transfers heat to a heat exchanger system (not shown), or when heating, transfers heat from the heat exchanger system. Moreover, gas can be delivered to the back-side of substrate 35 via a backside gas system to improve the gas-gap thermal conductance between substrate 35 and substrate holder 30. Such a system can be utilized when temperature control of the substrate is required at elevated or reduced temperatures. In other embodiments, heating elements, such as resistive heating elements, or thermo-electric heaters/coolers can be included.

[0023] In the illustrated embodiment shown in FIG. 1, substrate holder 30 can comprise an electrode through which RF power is coupled to the processing plasma in process space 12. For example, substrate holder 30 can be electrically biased at a RF voltage via the transmission of RF power from a RF generator (not shown) through an impedance match network (not shown) to substrate holder 30. The RF bias can serve to heat electrons to form and

maintain plasma. In this configuration, the system can operate as a reactive ion etch (RIE) reactor, wherein the chamber and upper gas injection electrode serve as ground surfaces. A typical frequency for the RF bias can range from approximately 1 MHz to approximately 100 MHz and can be approximately 13.56 MHz. RF systems for plasma processing are well known to those skilled in the art.

[0024] Alternately, the processing plasma in process space 12 can be formed using a parallel-plate, capacitively coupled plasma (CCP) source, or an inductively coupled plasma (ICP) source, or any combination thereof, and with or without magnet systems. Alternately, the processing plasma in process space 12 is formed from the launching of a Helicon wave. In yet another embodiment, the processing plasma in process space 12 is formed from a propagating surface wave.

[0025] Referring now to FIG. 2, a method of fabricating a baffle plate assembly, surrounding a substrate holder in a plasma processing system is described. As shown in FIG. 2, the method begins in 201 with first forming a baffle plate blank. The baffle plate blank is configured with one or more features that when modified by planar material removal form pumping passageways in the baffle plate blank, thus forming a baffle plate assembly. The baffle plate blank, including features to be modified, can be formed by metal casting, metal stamping, machining, ceramic fabrication, molding, or quartz fabrication, or any combination thereof. In 202, one or more pumping passageways are formed in the baffle plate blank by planar surface removal of the baffle plate blank. Planar material removal can be performed on at least one portion of one surface of the baffle plate blank. Planar surface removal to

baffle plate blank can be performed by milling, grinding, lapping, sanding, planing and/or etching. The planar surface removal process can be a single operation.

[0026] Referring now to an illustrated embodiment of the present invention as depicted in FIG. 3A, FIG. 3B and FIG. 3C. Baffle plate blank 300 is configured to be capable of surrounding a substrate holder in a plasma processing system. The baffle plate blank 300 is made from aluminum, alumina, silicon, quartz, carbon, silica nitride, and/or ceramic. The baffle plate blank 300 is configured with one or more closed pumping features 301. FIG. 3B identifies a cross-sectional view of baffle plate blank 300 illustrating several closed pumping features 301. Baffle plate blank has an upper surface 306 and a lower surface 307. As illustrated in FIG. 3C, when lower surface 307 is modified by planar material removal to form a new lower surface 308, open pumping passages 302 are formed in the baffle plate blank 300, thus forming a baffle plate assembly 310.

[0027] Furthermore a protective barrier can be formed on any surface of the baffle plate assembly 310. The protective barrier can, for example, facilitate the provision of an erosion resistant surface when the baffle plate assembly 310 is exposed to harsh processing environments, such as plasma. The protective barrier can be formed by providing a surface anodization on one or more surfaces, providing a spray coating on one or more surfaces, and/or subjecting one or more surfaces to plasma electrolytic oxidation. The protective barrier can comprise a layer of a III-column element and/or a Lanthanide element. The protective barrier can comprise Al_2O_3 , Yttria (Y_2O_3), Sc_2O_3 , Sc_2F_3 , YF_3 , La_2O_3 , CeO_2 , Eu_2O_3 , and/or DyO_3 . Methods of anodizing aluminum

components and applying spray coatings are well known to those skilled in the art of surface material treatment.

[0028] All surfaces on the baffle plate assembly 310 can be provided with the protective barrier, applied using any of the techniques described above. In another example, all surfaces on the baffle plate 310, except for a selected portion of a surface or surfaces, can be provided with the protective barrier, applied using any of the techniques described above. Prior to the application of the protective barrier to the surfaces of the baffle plate assembly 310, any region can be masked in order to prevent the formation of the barrier layer thereon. Alternatively, following the application of the protective barrier to the surfaces of the baffle plate assembly 310 any region can be processed to remove the barrier layer formed thereon.

[0029] In the embodiment shown in FIG. 3A, FIG 3B, and FIG. 3C, the one or more pumping passages 302 can comprise slots aligned in a radial direction. As shown, the slots can be spaced evenly azimuthally. In an alternate embodiment of the present invention, the slots can be spaced unevenly azimuthally. In an alternate embodiment of the present invention, the slots can be slanted and, therefore aligned, evenly partially in a radial direction and an azimuthal direction. In an alternate embodiment of the present invention, the slots can be slanted and, therefore aligned, unevenly partially in a radial direction and an azimuthal direction. In an alternate embodiment of the present invention the slots can be complex geometries aligned radially, slanted, evenly spaced and/or unevenly spaced. Indeed, the slots or other openings can be of any desired configuration. For example, FIG. 4A identifies a baffle plate assembly 410 with pumping passages 420 configured

in a complex slot configuration, centered with respect to the baffle plate assembly 410 and evenly spaced azimuthally.

[0030] Alternately the pumping passages can include at least one orifice. Alternately, as shown in FIG. 4B, the pumping passages 440 comprise a plurality of orifices having a constant size and uniform distribution on the baffle plate assembly 430. Alternately the pumping passages can comprise a plurality of orifices, wherein the orifice size, distribution (or number density), and/or orifice shape varies across a baffle plate assembly. For example, when a vacuum pump (not shown) accesses a processing chamber 10 through a pumping duct 40, as shown in FIG. 1, the number of pumping passages can be reduced local to the entrance to the pumping duct 40 in order to correct for the non-uniform pressure field inherent to such an arrangement.

[0031] Alternately pumping passages can include at least one slot and at least one orifice. Varieties of alternate arrangements of these pumping features can utilize any of the alternates described above or any other shape or configuration.

[0032] The orifice described above can be a round hole, a polygon, an icon, letters of any language and/or any open geometric shape. For example, FIG. 4C identifies a baffle plate assembly 450 with multiple orifices 460, comprised of English language characters.

[0033] Although only certain exemplary embodiments of this invention have been described in detail above, those skilled in the art will readily appreciate that many modifications are possible in the exemplary embodiments without materially departing from the novel teachings and advantages of this

invention. Accordingly, all such modifications are intended to be included within the scope of this invention.

CLAIMS:

1. A method of fabricating a baffle plate assembly, surrounding a substrate holder in a plasma processing system comprising:
forming a baffle plate blank; and
forming one or more pumping passageways wherein one or more features of said baffle plate blank are modified by planar material removal forming said pumping passages.
2. A method according to claim 1 wherein said forming of said baffle plate blank includes metal casting, metal stamping, machining, ceramic fabrication, molding, or quartz fabrication, or any combination thereof.
3. A method according to claim 1, wherein said planar material removal modification to said blank baffle plate blank comprises milling, grinding, lapping, sanding, planing, or etching, or any combination thereof.
4. The method according to claim 1, wherein the planar material removal is performed in a single operation.
5. A baffle plate assembly, surrounding a substrate holder in a plasma processing system comprising:
a baffle plate blank having one or more pumping passages, wherein one or more features of said baffle plate blank are modified by planar material removal to form said pumping passages
6. A baffle plate assembly according to claim 5, wherein said baffle plate blank is made from aluminum, alumina, silicon, quartz, carbon, silicon nitride, silicon carbide, or ceramic, or any combination thereof.
7. A baffle plate assembly according to claim 5, wherein a surface of said baffle plate assembly comprises a protective barrier.

8. A baffle plate assembly according to claim 5, wherein a portion of a surface of said baffle plate assembly comprises a protective barrier.
9. A baffle plate assembly according to claim 7 or 8, wherein said protective barrier comprises a surface anodization, a coating formed using plasma electrolytic oxidation, or a spray coating, or any combination thereof.
10. A baffle plate assembly according to claim 7 or 8, wherein said protective barrier comprises a layer of one or more III-column elements or one or more Lanthanum elements, or any combination thereof.
11. A baffle plate assembly according to claim 10, wherein said one or more III-column elements comprise Yttrium, Scandium, or Lanthanum, or any combination thereof.
12. A baffle plate assembly according to claim 11, wherein said one or more Lanthanum elements comprise Cerium, Dysprosium, or Europium, or any combination thereof.
13. The baffle plate assembly according to claim 7 or 8, wherein said protective barrier comprises Al_2O_3 , Yttria (Y_2O_3), Sc_2O_3 , Sc_2F_3 , YF_3 , La_2O_3 , CeO_2 , Eu_2O_3 , or DyO_3 , or any combination thereof.
14. A baffle plate assembly according to claim 5, wherein one or more said pumping passages comprises a slot, or an orifice, or any combination thereof.
15. An orifice according to claim 14, wherein the shape and design of said orifice is a round hole, a polygon, an icon, one or more letters of any language, or any open geometric shape.
16. A baffle plate assembly according to claim 5, wherein the size, shape or distribution of said pumping passages, or any combination thereof, varies on said baffle plate assembly.

17. A plasma process apparatus with baffle plate assembly comprising:
- a process chamber,
 - a plasma generating system configured and arranged to produce a plasma in the process chamber,
 - a gas source configured to introduce gases into the process chamber,
 - a pressure control system to maintain a selected pressure within the process chamber,
 - a substrate holder configured to hold a substrate during substrate processing,
 - and
 - a baffle plate assembly disposed radially outward from said substrate and formed from a baffle plate blank with one or more pumping passages formed by planar material removal from said baffle plate blank.

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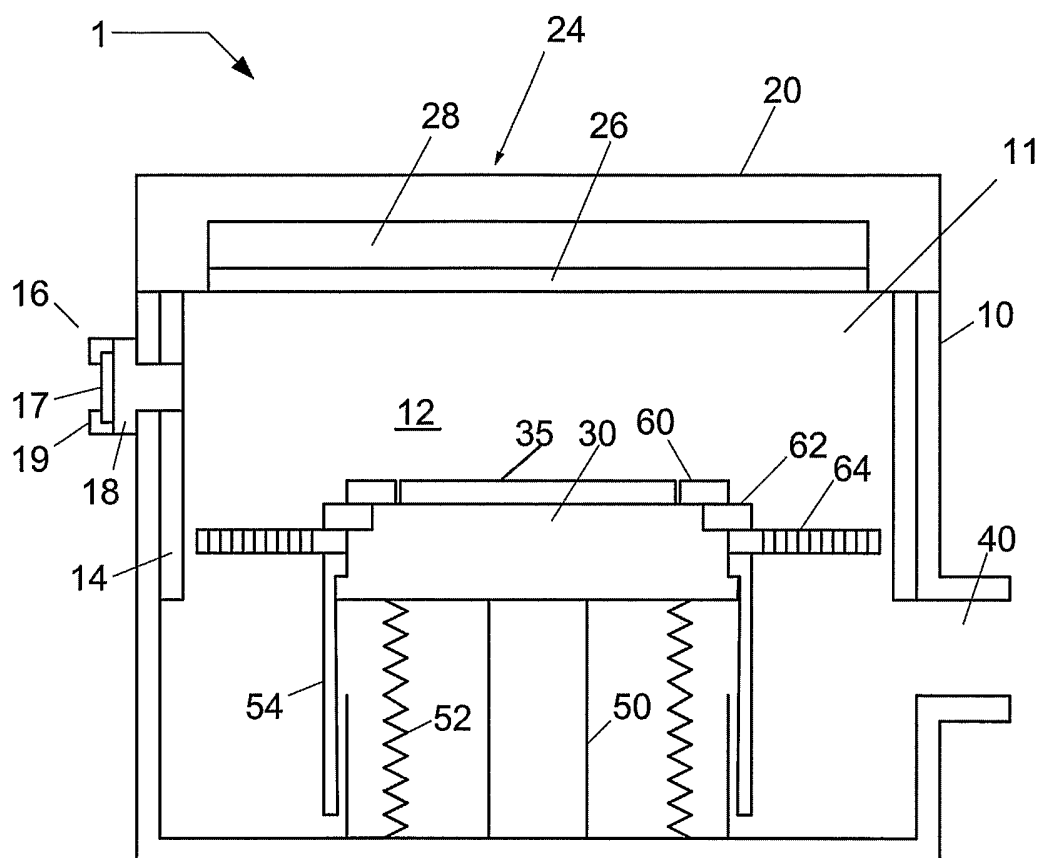


FIG. 1

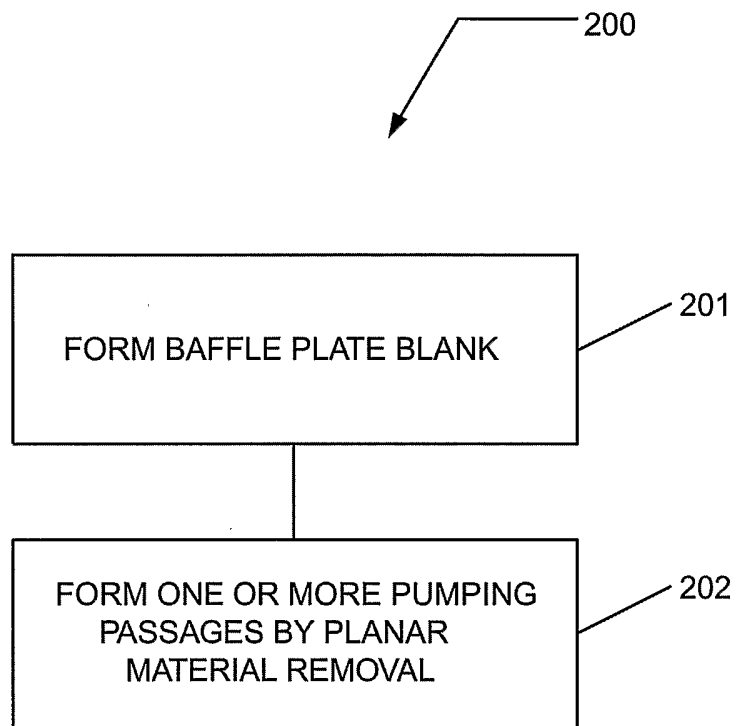
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FIG. 2

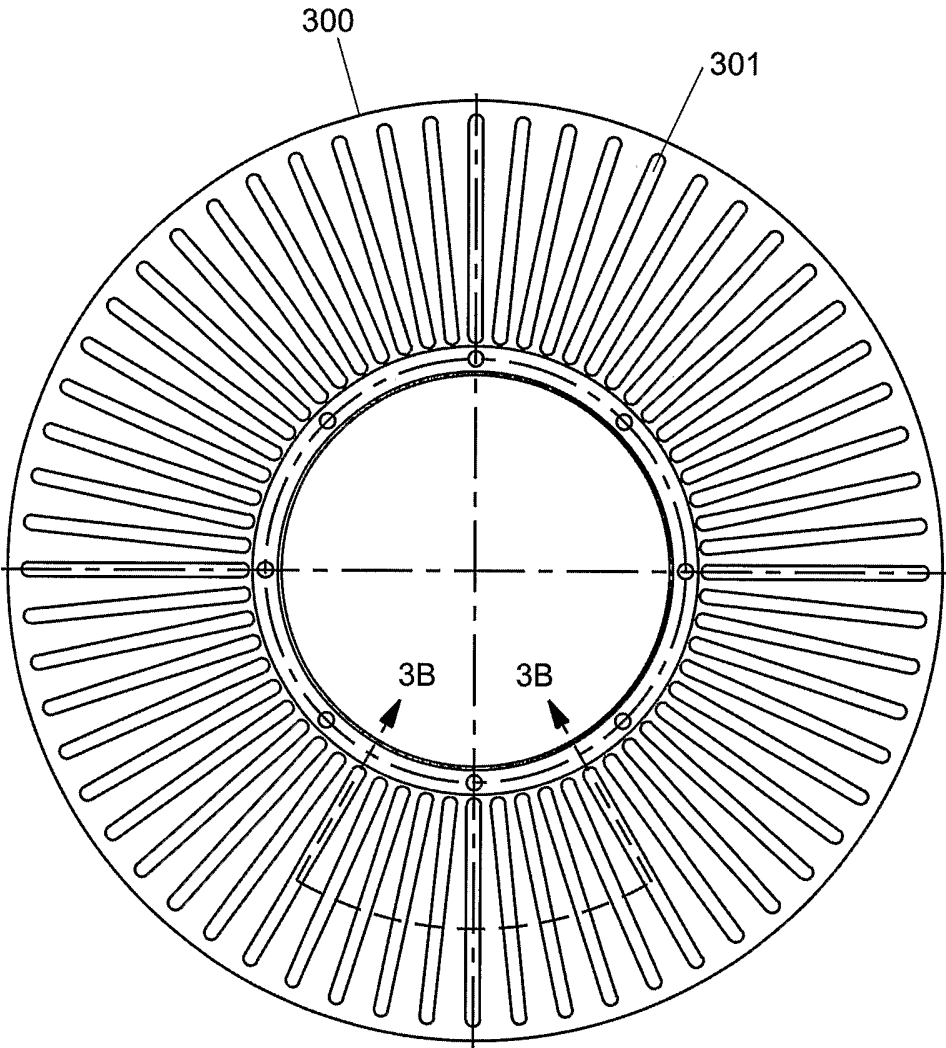


FIG. 3A

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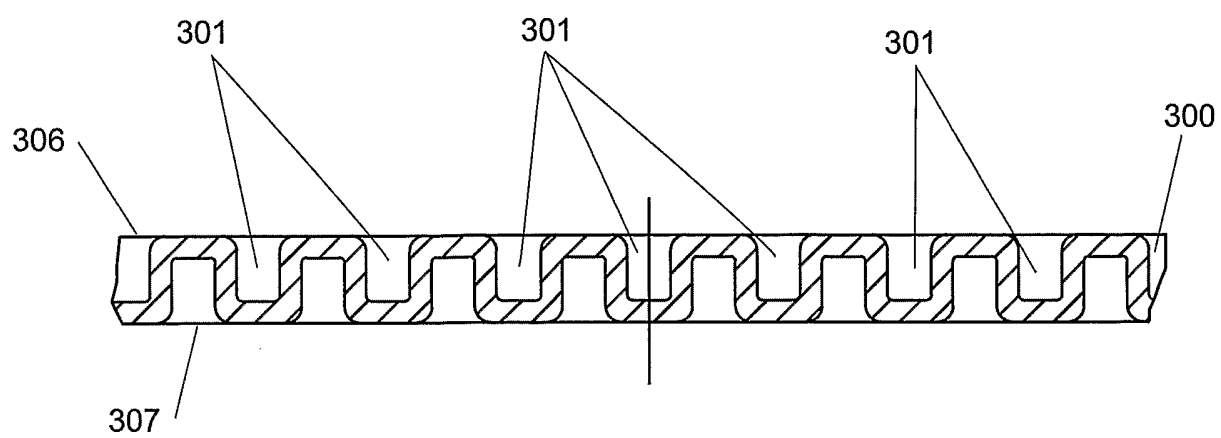


FIG. 3B

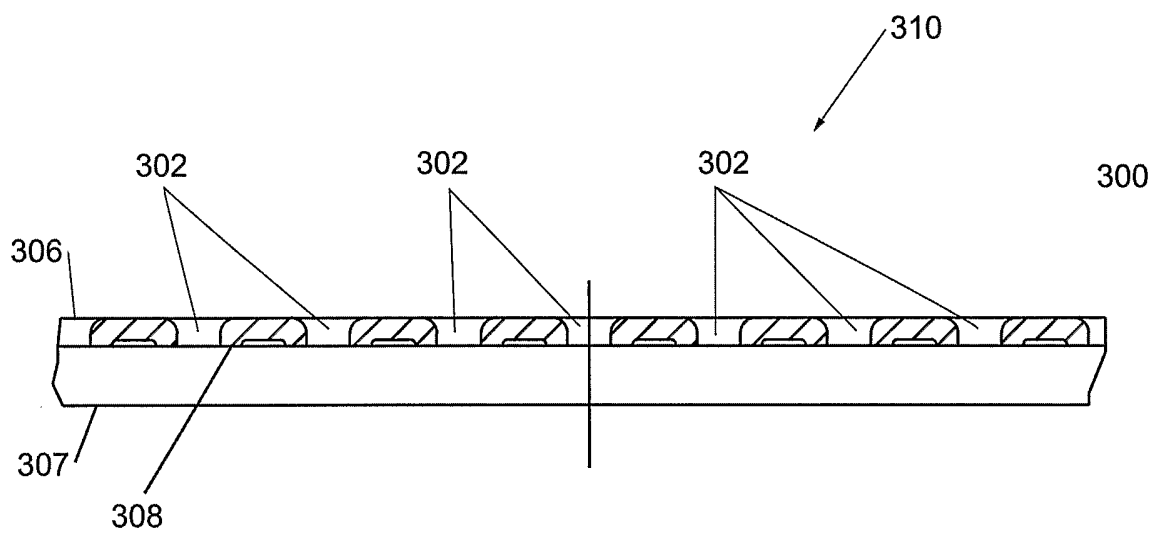


FIG. 3C

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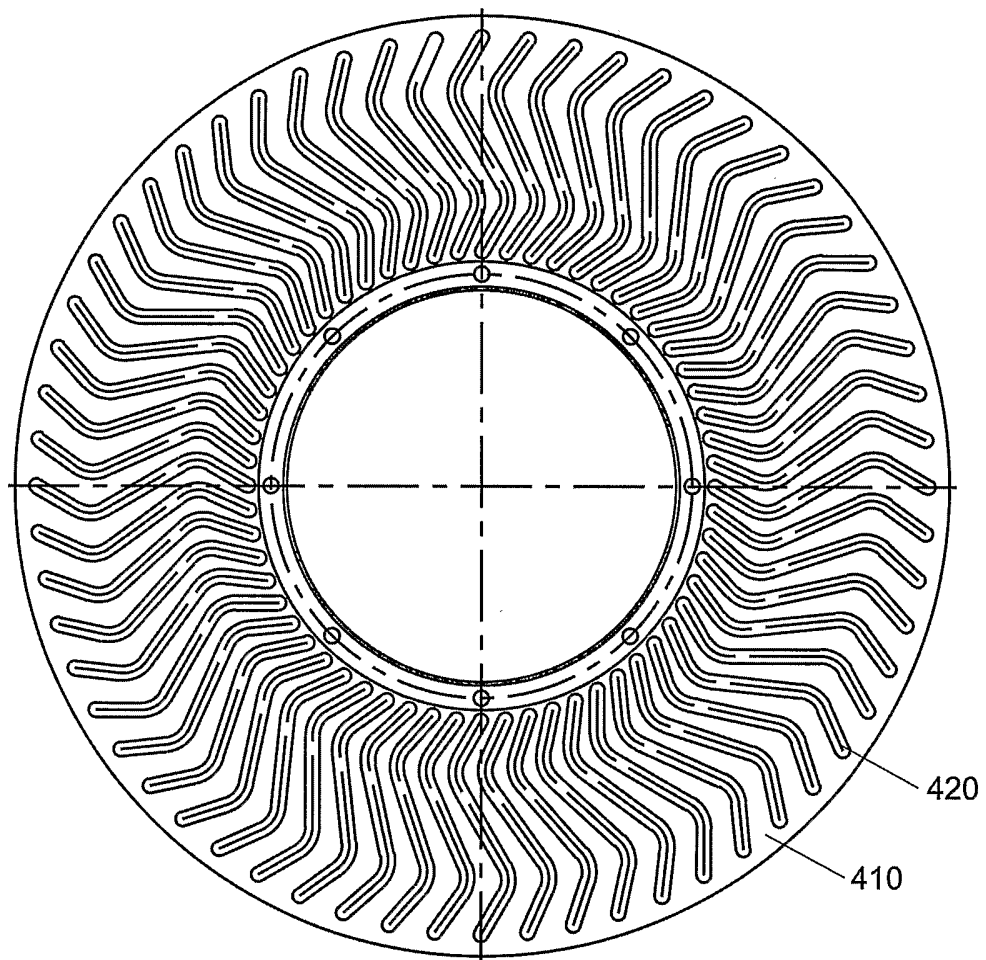


FIG. 4A

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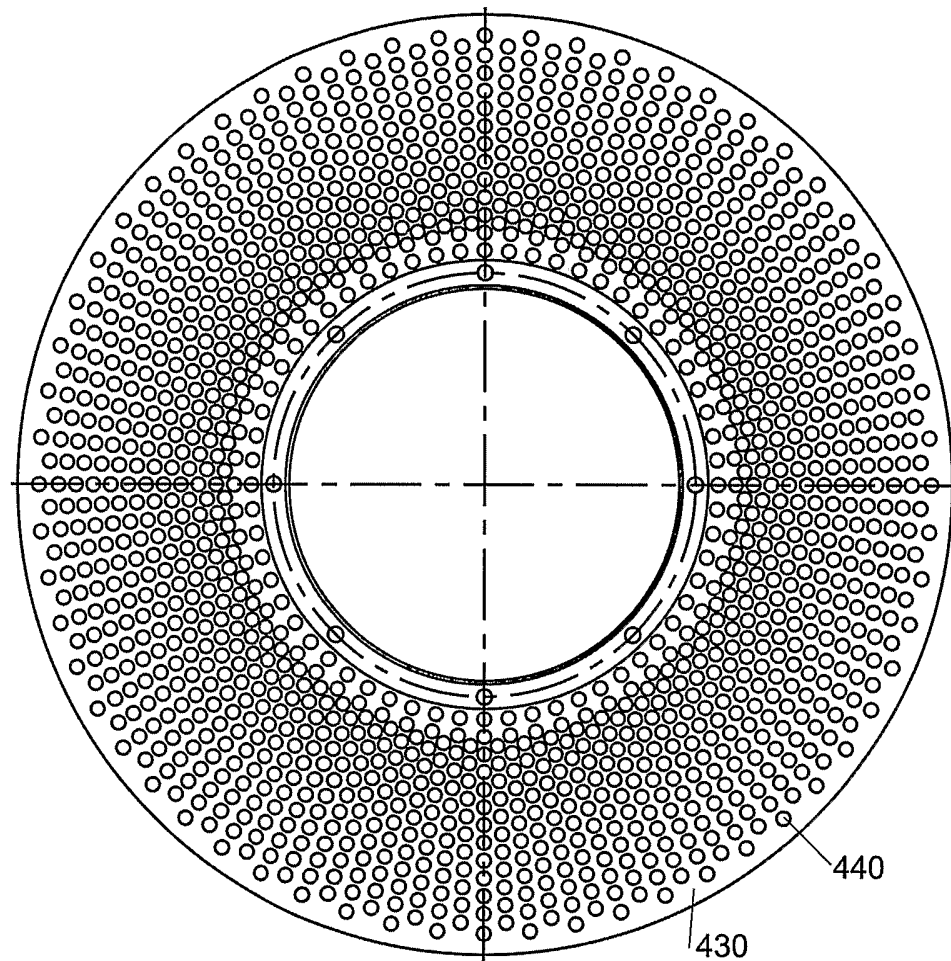


FIG. 4B

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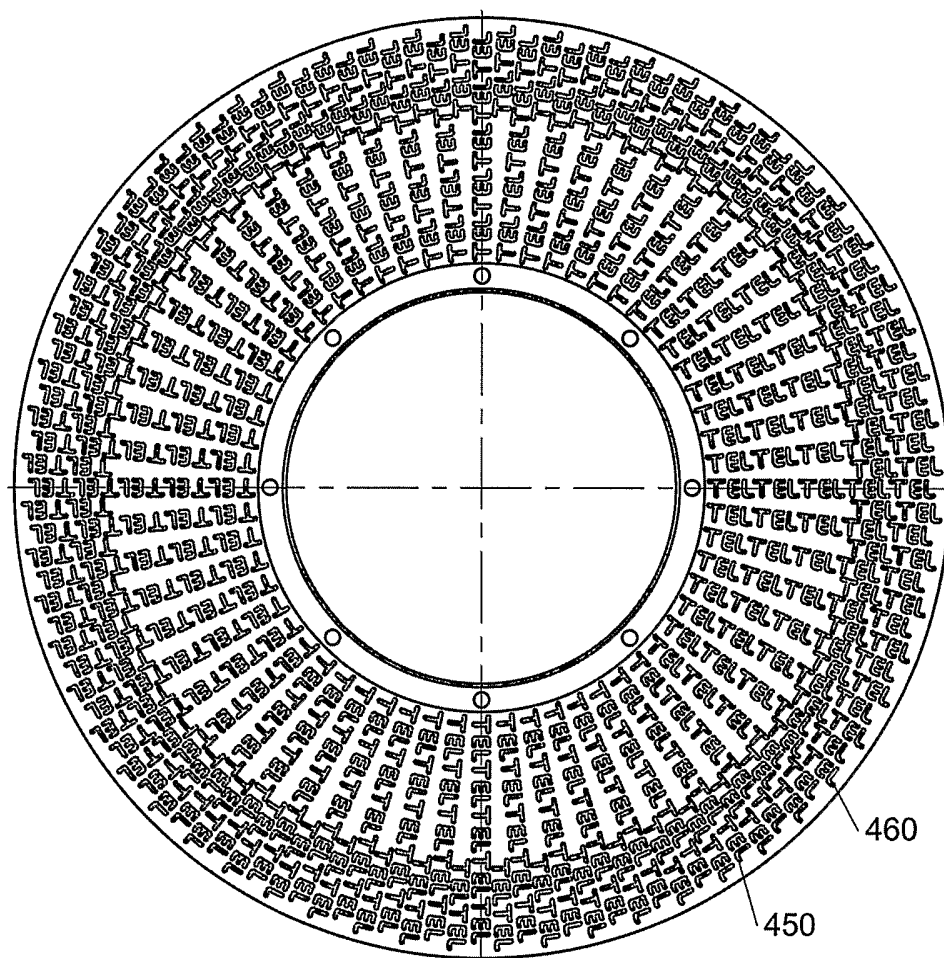


FIG. 4C